

Attorney Docket: 081468-0307456  
Client Reference: P-1794.000-US



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:  
BANINE ET AL.

Confirmation Number: 2894

Application No.: 10/747,613

Group Art Unit: 2851

Filed: December 30, 2003

Examiner: Della J. Rutledge

Title: LITHOGRAPHIC APPARATUS AND RADIATION SOURCE COMPRISING A  
DEBRIS-MITIGATION SYSTEM AND METHOD FOR MITIGATING DEBRIS PARTICLES  
IN A LITHOGRAPHIC APPARATUS

AMENDMENT

United States Patent and Trademark Office  
Customer Service Window  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

In response to the Office Action dated February 10, 2005, a response to which being due August 10, 2005 with a three-month extension being filed herewith, please amend the above-identified application as follows:

08/11/2005 SZEWDIE1 00000131 033975 10747613

01 FC:1253 1020.00 DA